

Characterization of Delayed Crosstalk of SiPM

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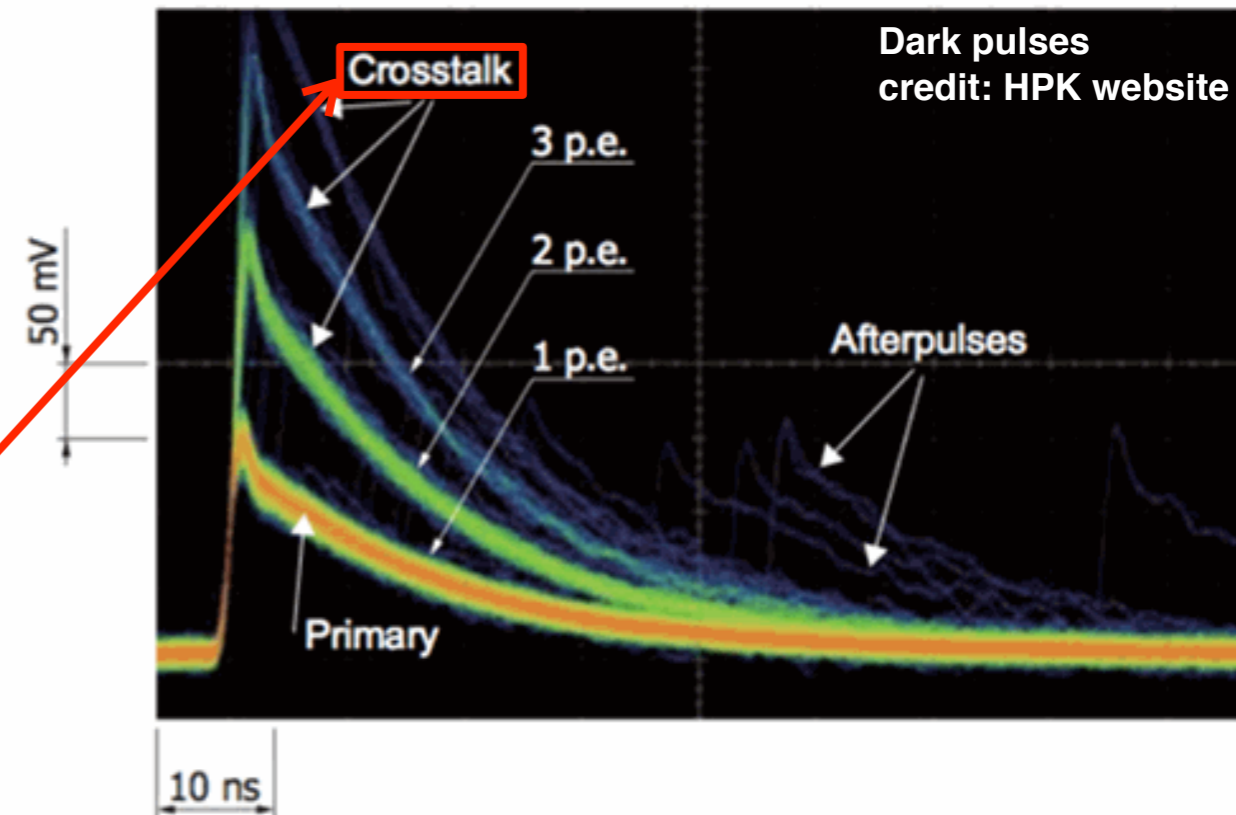
**Institute for Space–Earth Environmental Research
Nagoya University**



**cherenkov
telescope
array**

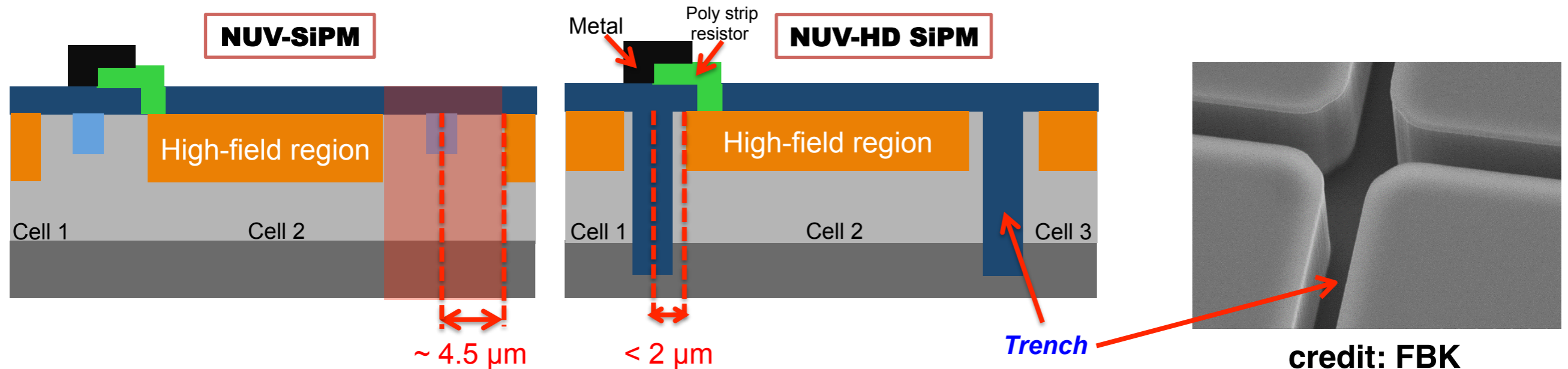
**Japan Physical Society Meeting
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- ❖ **Silicon Photomultiplier** is chosen as a photon sensor for many experiments
 - ❖ Cost per channel
 - ❖ Tolerance against **high rate environment**
 - ❖ Photon detection efficiency
 - ❖ Reliability

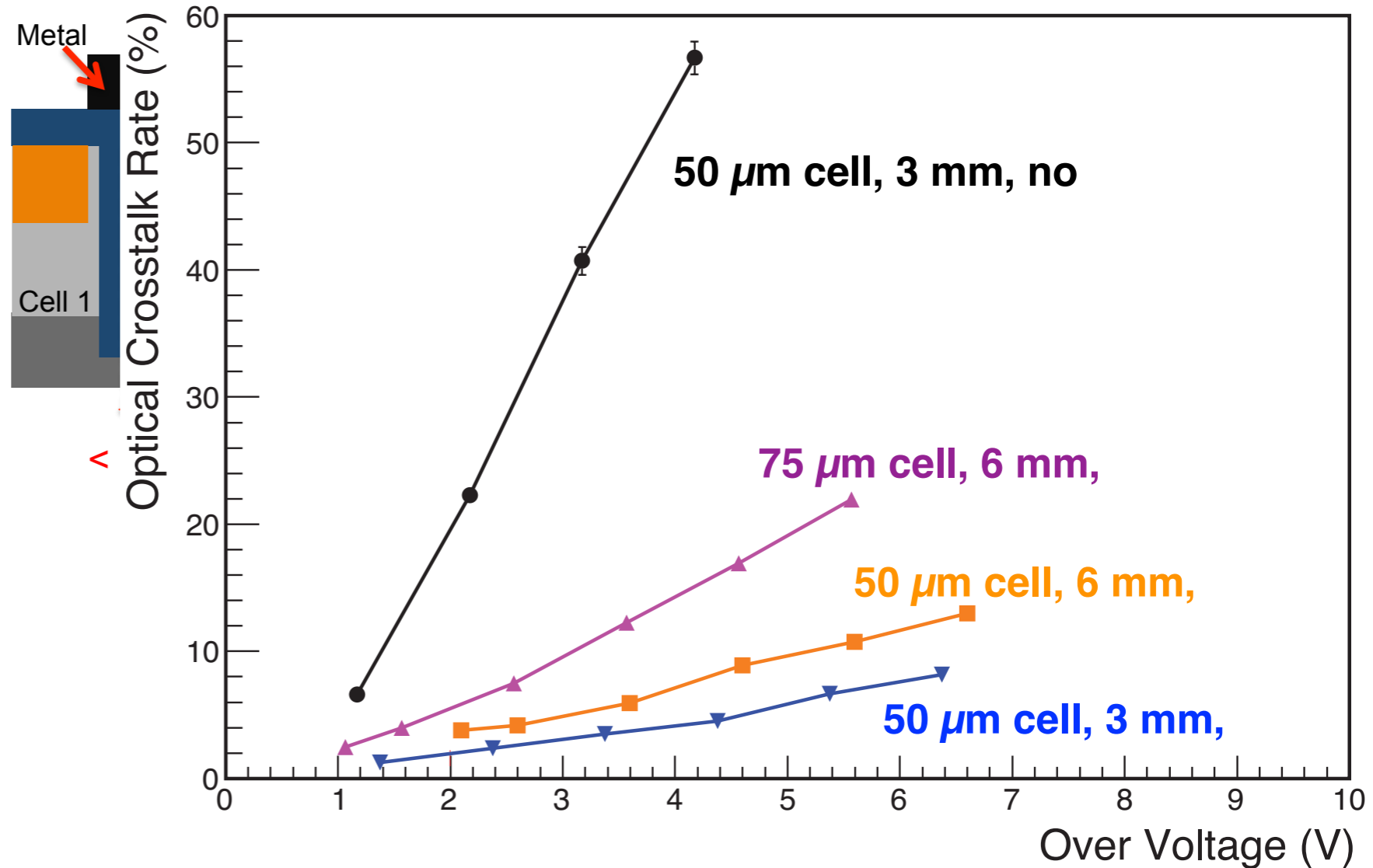
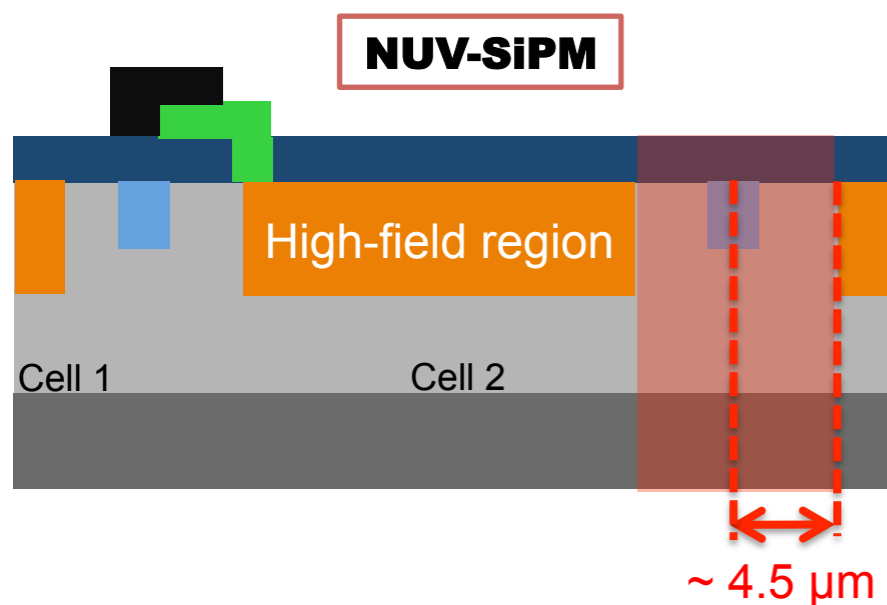


- ❖ Major drawback of SiPM
 - ❖ **Optical crosstalk (OCT)**
 - ❖ Gain dependence on the temperature
- ❖ Main objective of this study
 - ❖ **Suppress OCT while retaining photon detection efficiency (PDE)**

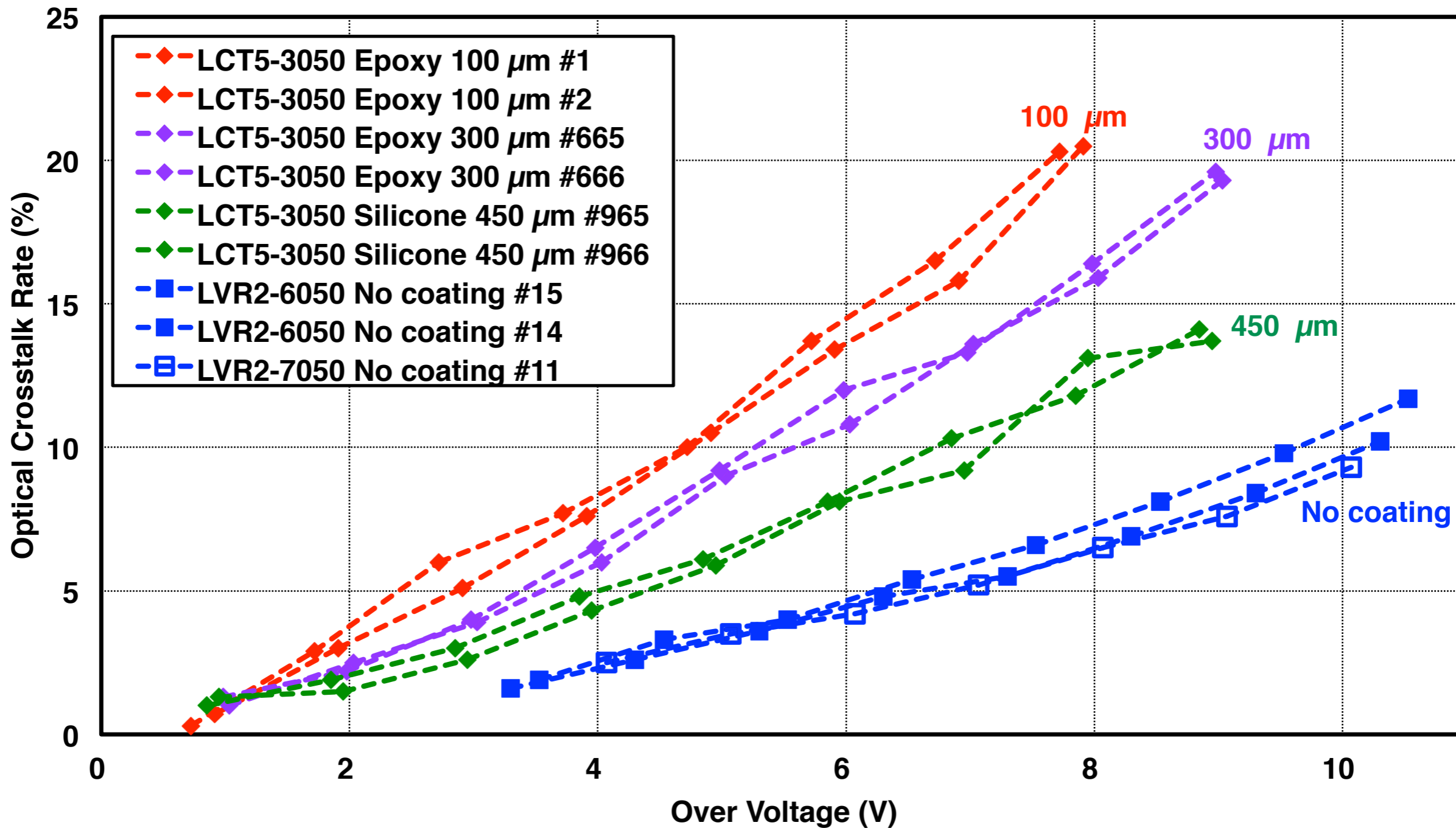
- ❖ Optical crosstalk is caused by photons produced in primary avalanche
- ❖ Trench is implemented to prevent photons from crossing cell boundary
- ❖ Narrower trench gives better fill factor



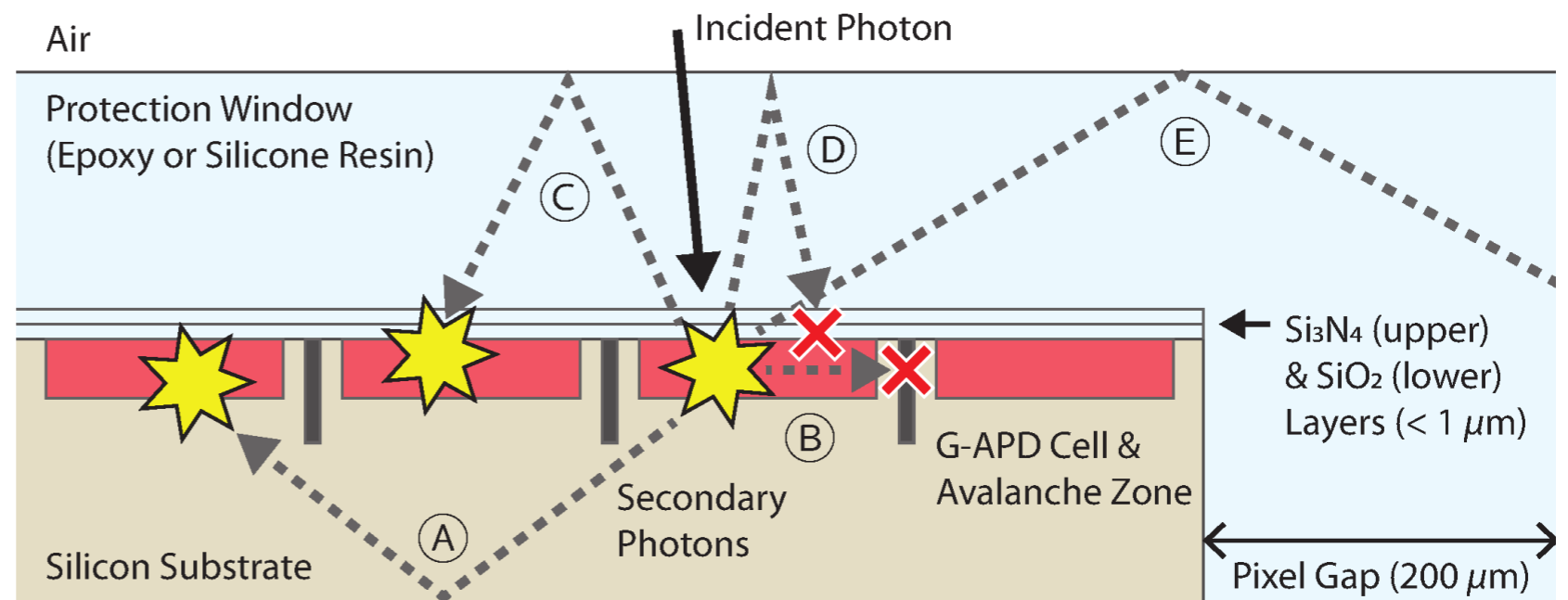
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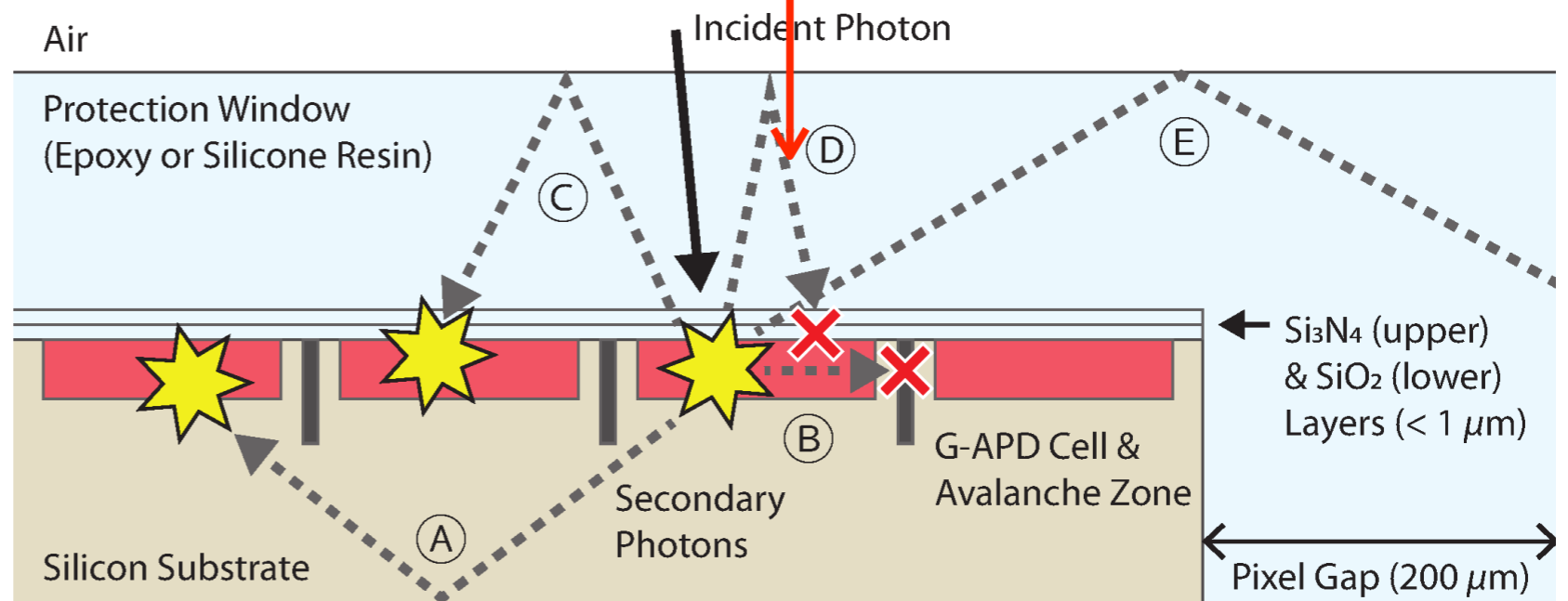
❖ **Thicker coating or no coating give lower crosstalk**



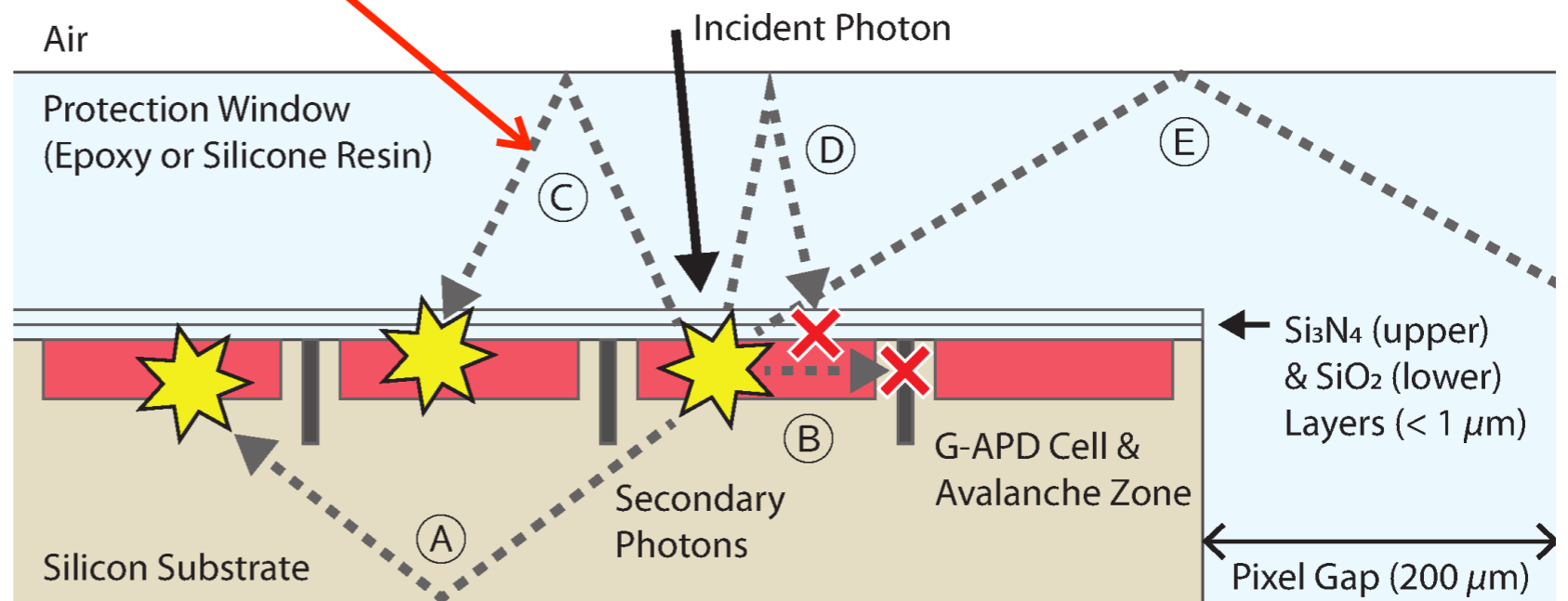
- ❖ No coating (or very thin coating)
 - ❖ Reflected photons come back to the original cell
- ❖ Intermediate thickness
 - ❖ Photons reflected by the air interface may produce avalanches in other cells
- ❖ Very thick coating
 - ❖ Photons reflected by the air interface may get out of the device
 - ❖ Smaller device may have lower crosstalk rate



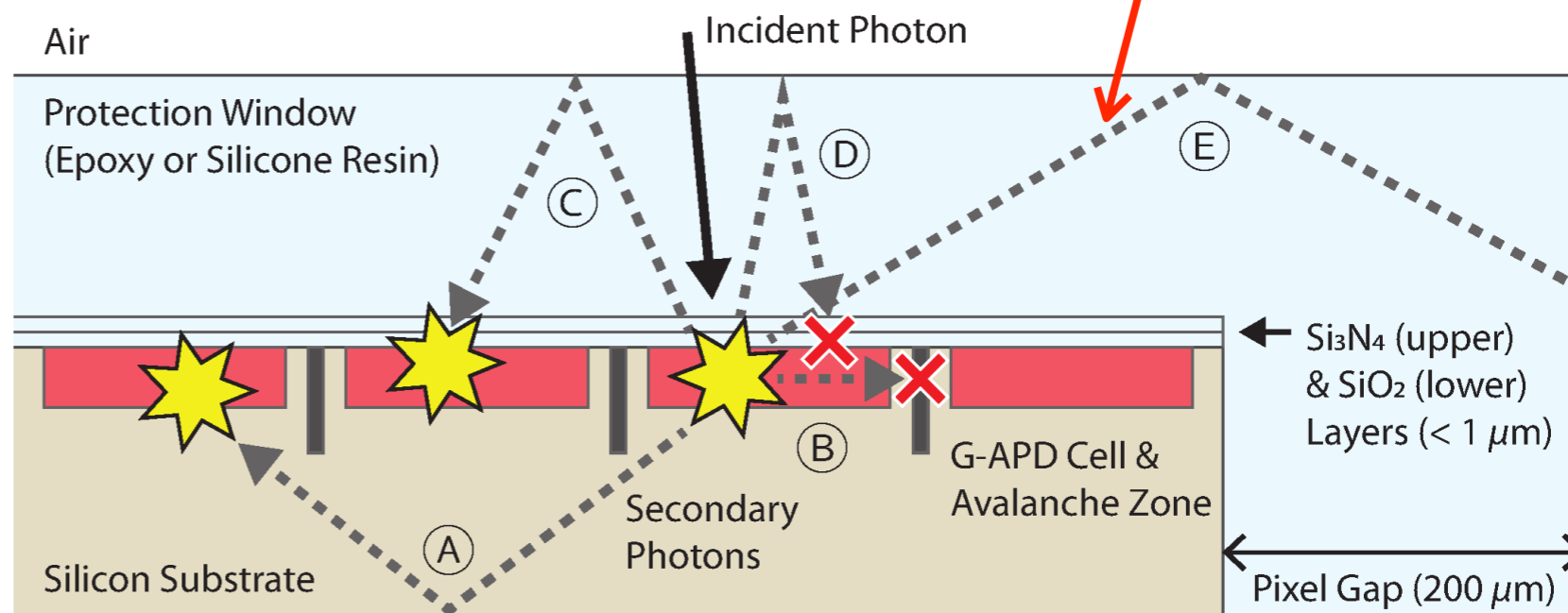
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- ❖ We have systematically investigated the OCT rate with varying device size, cell size, and with and without coating
- ❖ OCT rate is expected to be proportional to the number of electron-holes pairs (=charge) produced in an avalanche
 - ❖ proportional to a product of [cell capacitance] and [over voltage]
- ❖ Find out propagation properties of crosstalk photons

Product ID	Device size	Cell size	Coating	Fill factor
S14520-3050VS	3 mm	50 μm	300 μm	74%
S14520-3050VN	3 mm	50 μm	None	74%
S14520-3075VS	3 mm	75 μm	300 μm	82%
S14520-3075VN	3 mm	75 μm	None	82%
S14520-6050VS	6 mm	50 μm	300 μm	74%
S14520-6050VN	6 mm	50 μm	None	74%
S14520-6075VS	6 mm	75 μm	300 μm	82%
S14520-6075VN	6 mm	75 μm	None	82%

❖ Take waveform data by digital oscilloscope

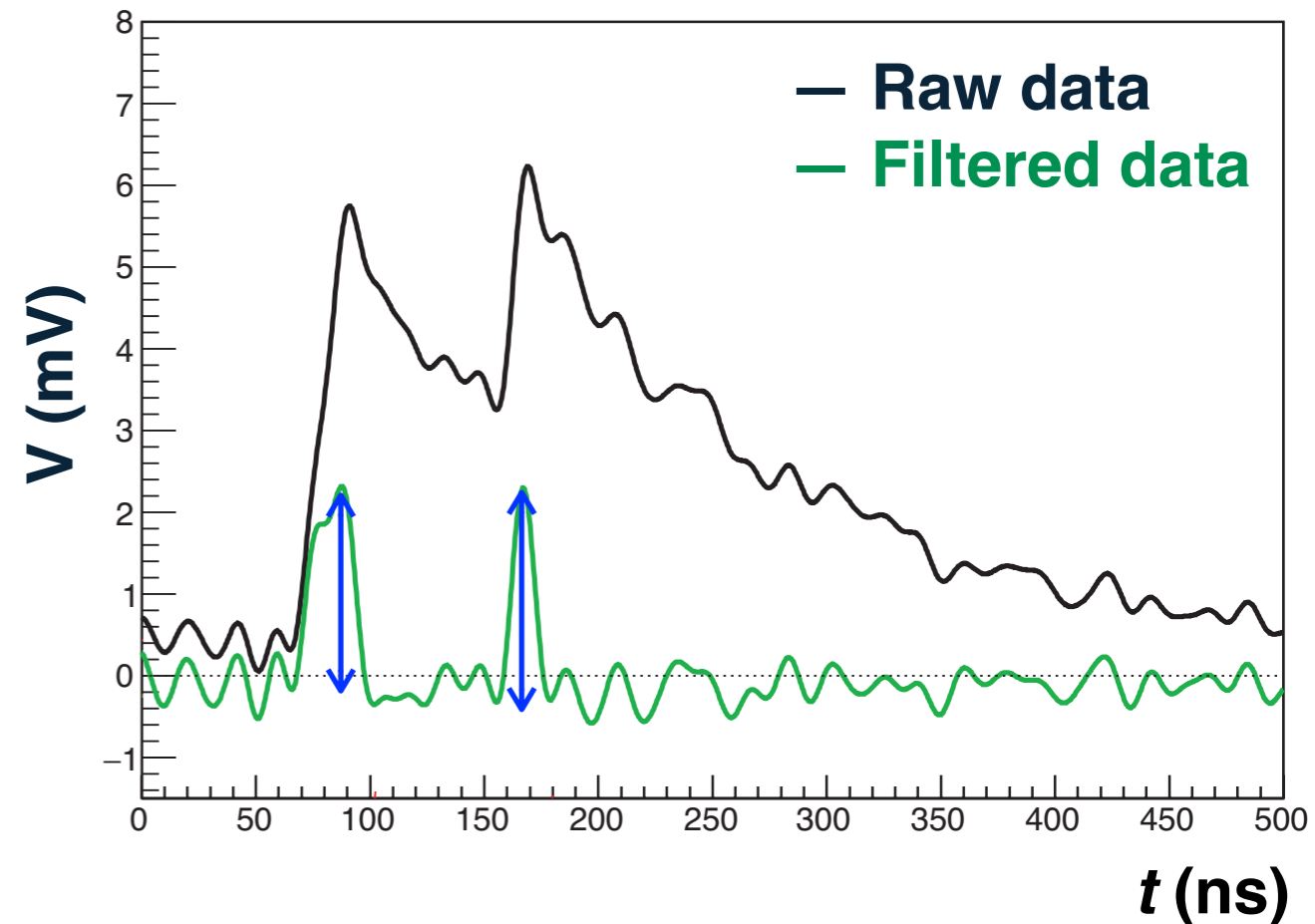
❖ Offline data analysis

◆ Digital filter to minimize the effect of pile ups

◆ Fit the data with multiple pulses

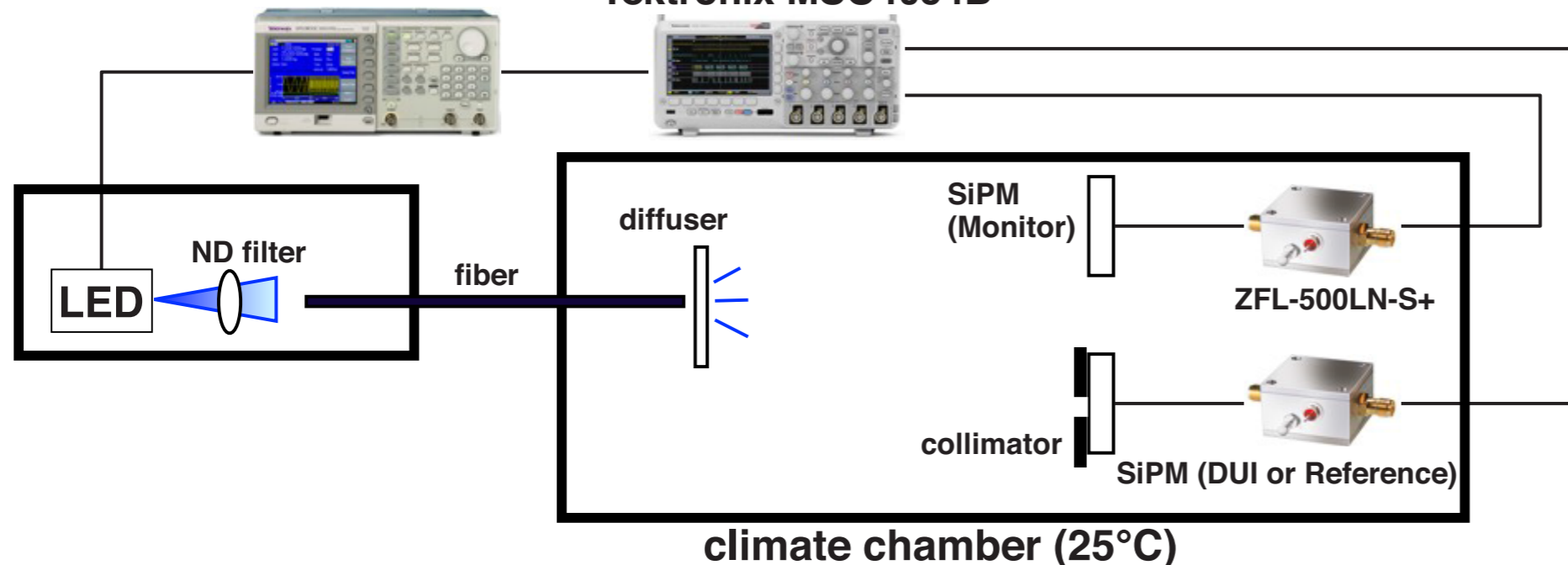
❖ Light output is monitored

❖ Wavelength is fixed at 405 nm for this measurement

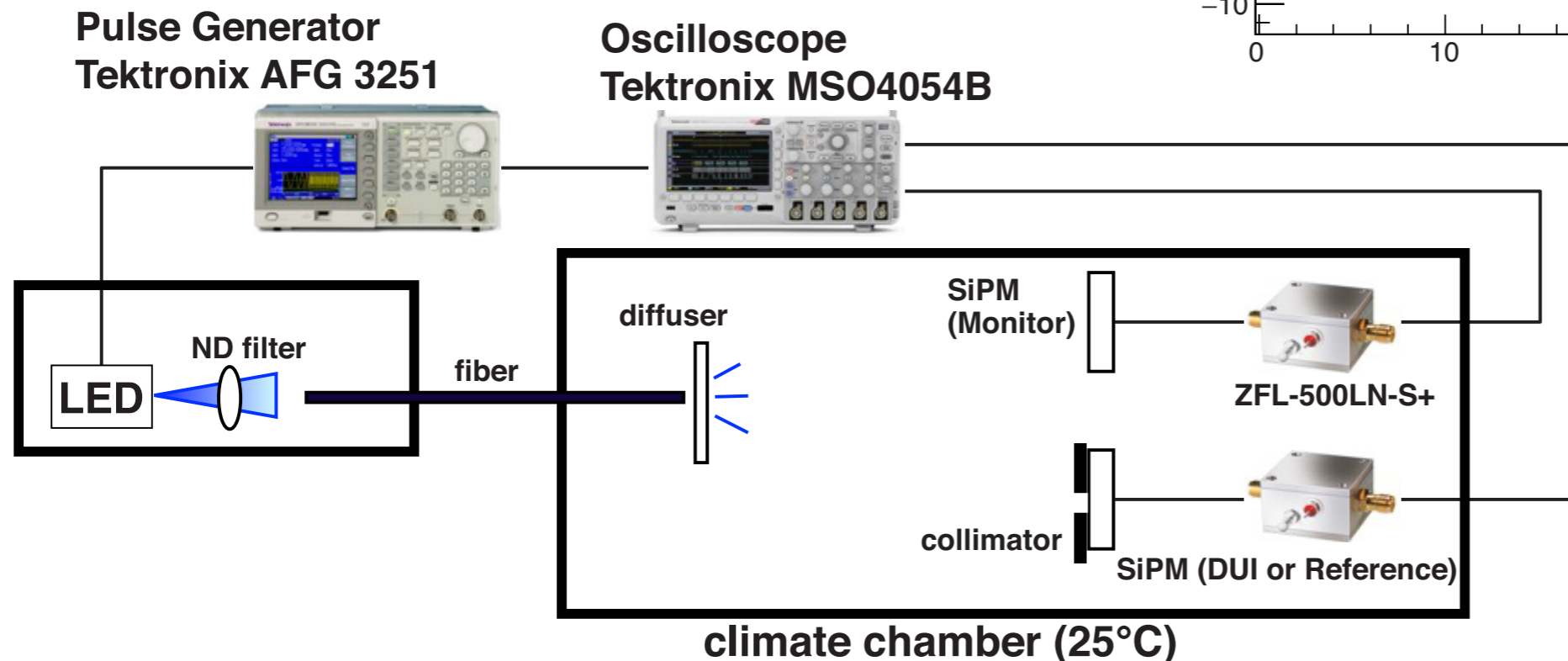
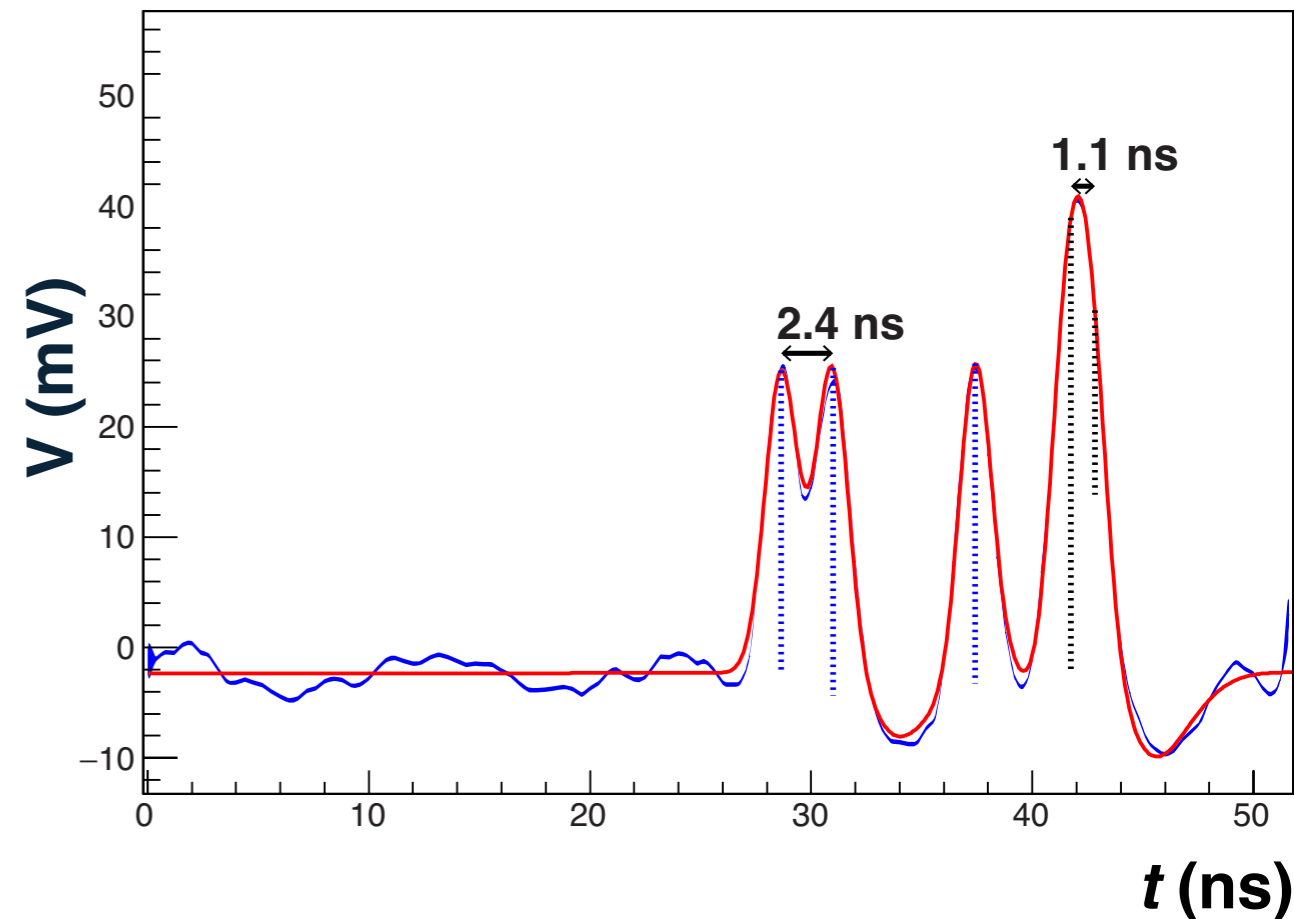


Pulse Generator
Tektronix AFG 3251

Oscilloscope
Tektronix MSO4054B



- ❖ Take waveform data by digital oscilloscope
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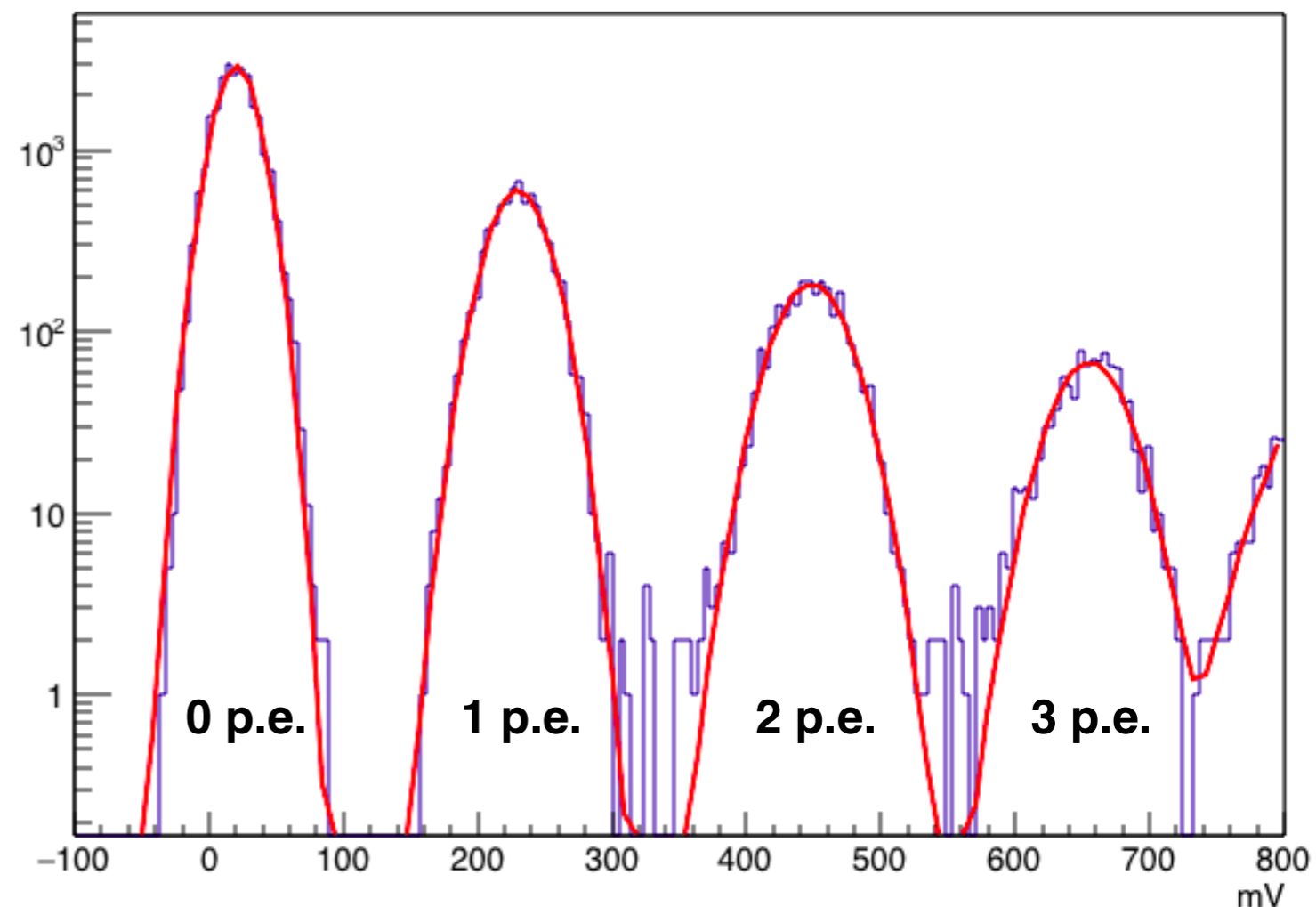
- ❖ We measure number of photons for short LED (or laser) pulses
 - ❖ Current measurement does not provide accurate PDE due to optical crosstalk, delayed cross talk and after pulse
- ❖ Number of photo electrons (p.e.) does not follow Poisson distribution due to optical crosstalk
 - ❖ **Probability of 0 p.e.** is used to obtain the average to avoid effects of optical crosstalk
 - ❖ **Effect of dark count** still need to be taken into account

$$P(n) = e^{-\mu} \mu^n / n!$$

$$P(0) = e^{-\mu}$$

$$\mu = -\ln(P(0))$$

$$P_{\text{true}}(0) = P_{\text{ON}}(0) / P_{\text{OFF}}(0)$$

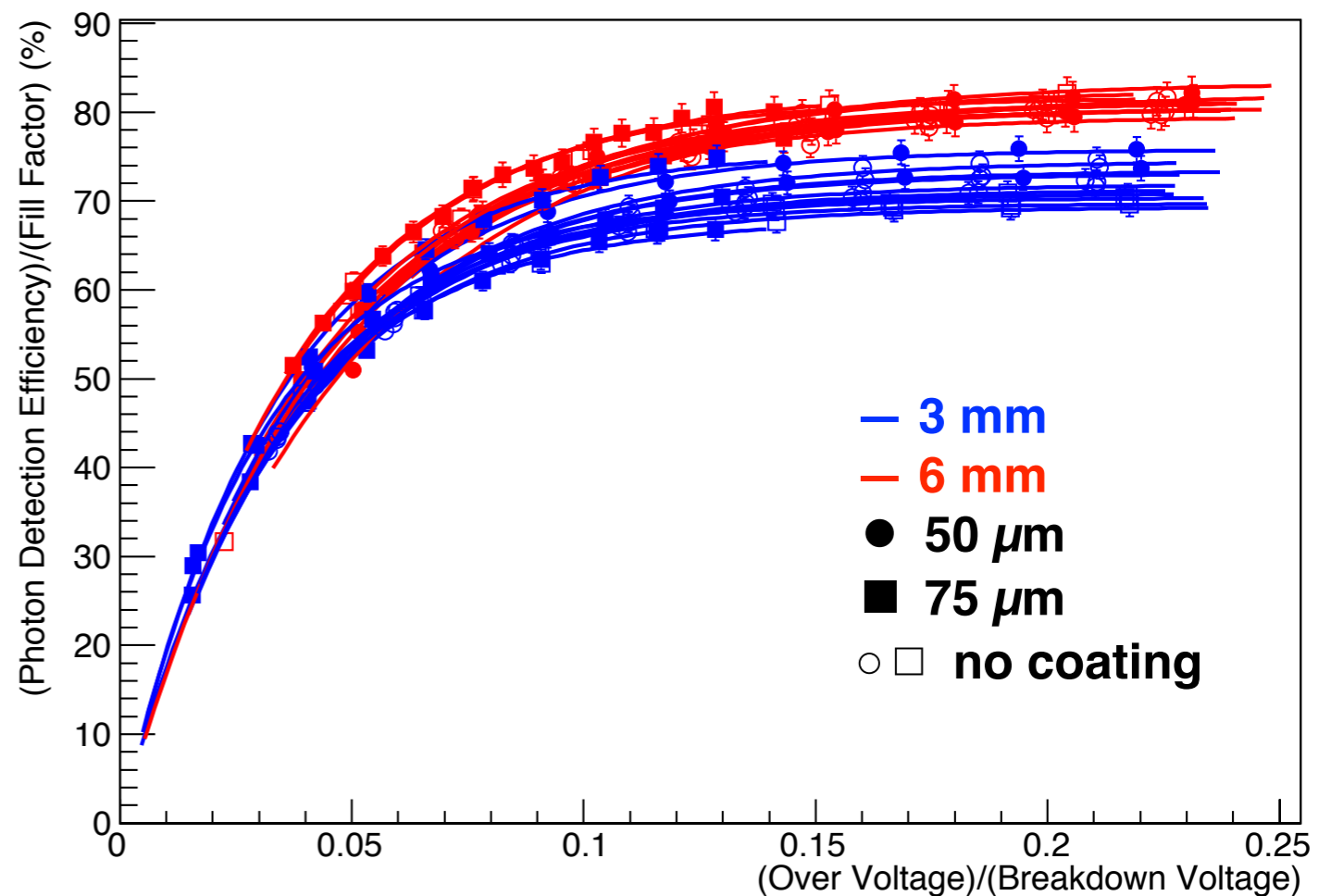
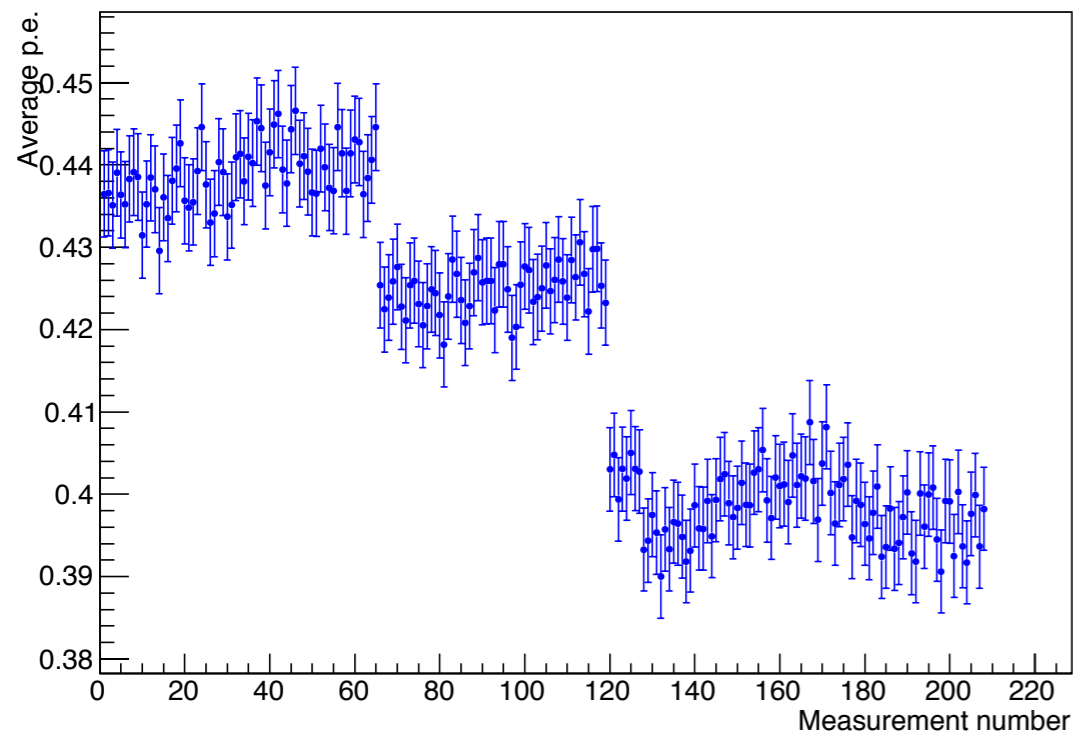


- ❖ PDEs were measured for 2 devices for each type
- ❖ PDEs were measured twice for some devices
- ❖ Measured PDEs were very consistent, which indicates varying light intensity is properly compensated by the monitor SiPM

Avalanche probability

$$\text{PDE}/(\text{Fill factor}) = \text{PDE}_{\text{max}} \cdot (1 - \exp[-C_{\text{depth}} V_{\text{OV}}/V_{\text{BR}}])$$

Average p.e. for Monitor SiPM



- ❖ Assume 1 p.e. peak of dark signal is dominated by dark count
- ❖ 2 p.e. peak consists of optical crosstalk from 1 p.e. and chance coincidence of dark counts within Δt_{PS} (~ 3 ns in our setup)

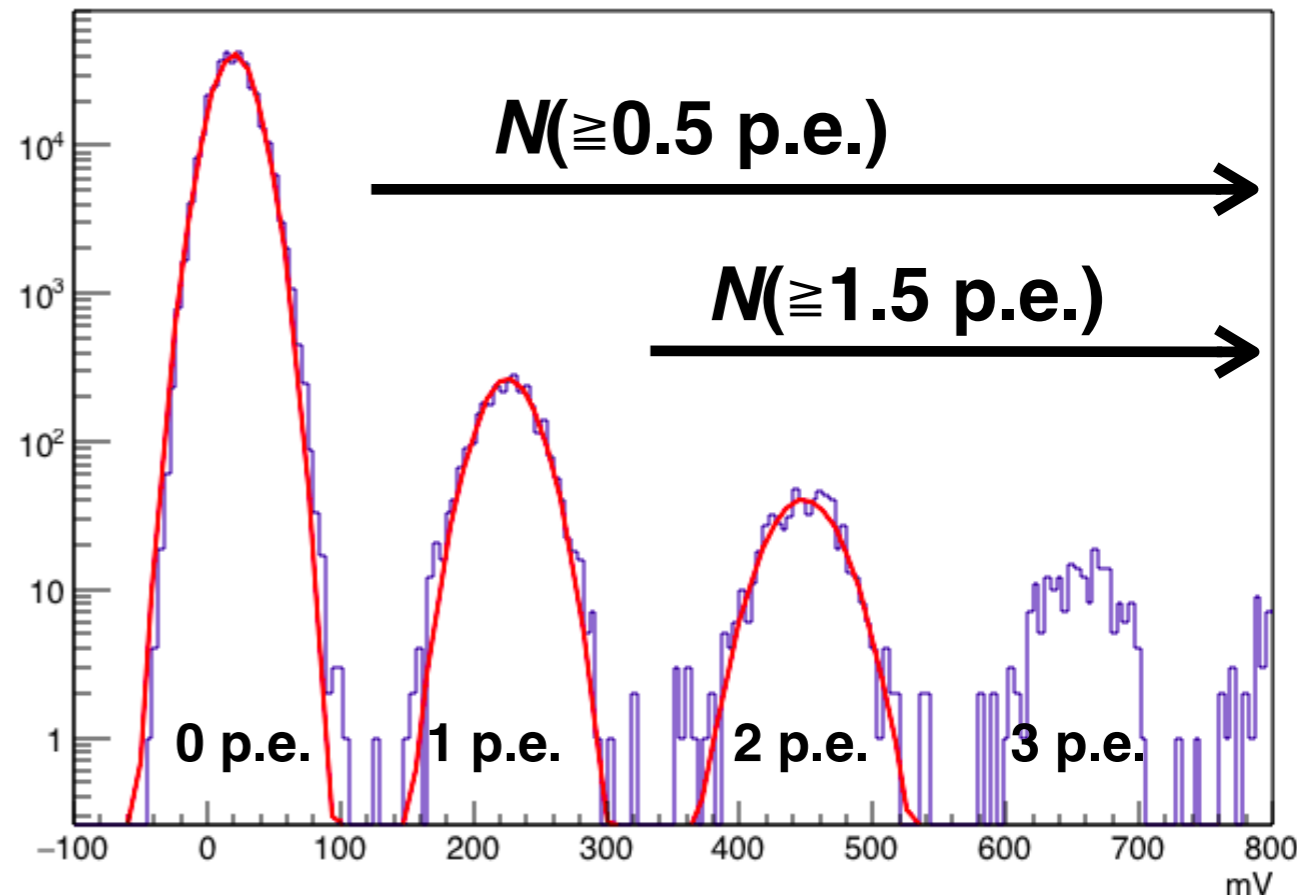
Probability to have no optical crosstalk

$$\frac{N(\geq 1.5 \text{ p.e.})}{N(\geq 0.5 \text{ p.e.})} = 1 - \boxed{(1 - R_{OCT})e^{-f_{DC}\Delta t_{PS}}} \leftarrow \text{Poisson probability to have no overlapping dark count within } \Delta t_{PS}$$

$$R_{OCT} = 1 - \left(1 - \frac{N(\geq 1.5 \text{ p.e.})}{N(\geq 0.5 \text{ p.e.})} \right) / e^{-f_{DC}\Delta t_{PS}}$$

f_{DC} : Dark count rate

Δt_{PS} : Double-pulse separation time



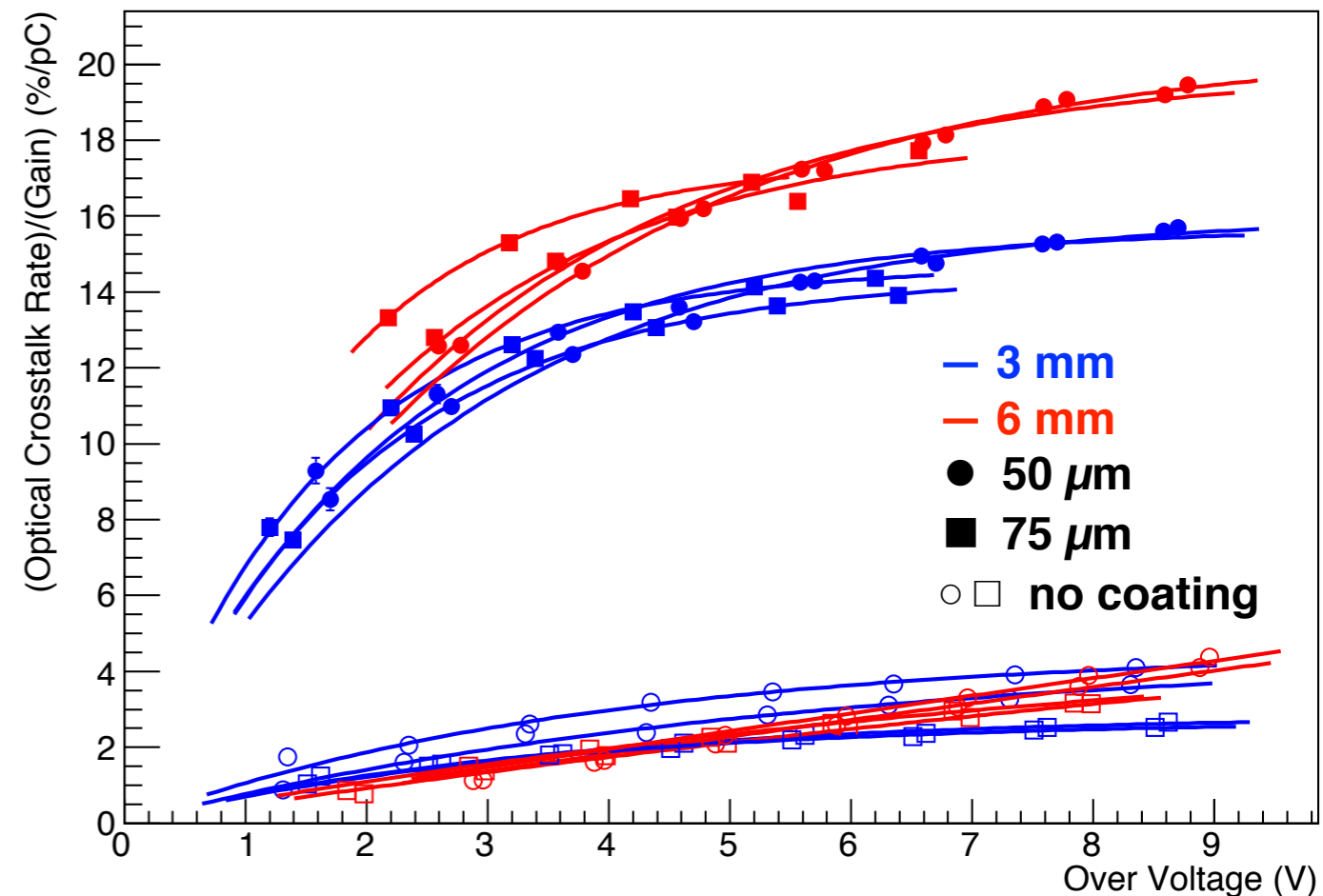
❖ Optical crosstalk rate should be proportional to the gain and avalanche trigger probability

$$R_{OCT}/(\text{Gain}) = C_{OCT} \cdot \overset{\text{Avalanche probability}}{(1 - \exp[-C'_{\text{depth}} V_{OV}/V_{BR}])}$$

❖ C_{depth} tends to be small without resin coating

◆ **Avalanche seed is produced in the region where it is harder to trigger avalanche**

Product ID	C_{OCT}	C_{depth}
S14520-3050VS	16	17
S14520-6050VS	20	14
S14520-3075VS	14	23
S14520-6075VS	18	22
S14520-3050VN	4.5	9
S14520-6050VN	50	0.4
S14520-3075VN	3	11
S14520-6075VN	7	3



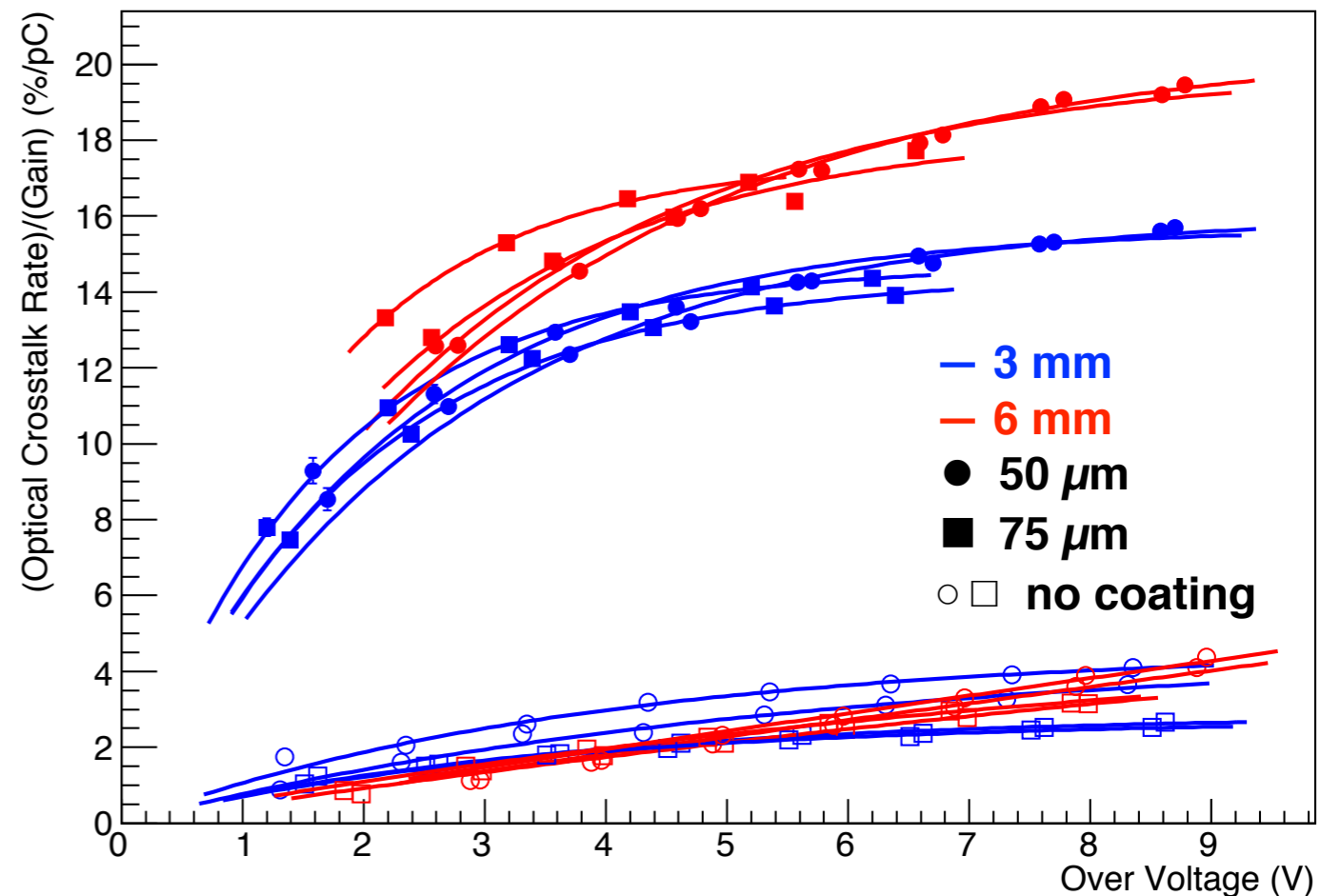
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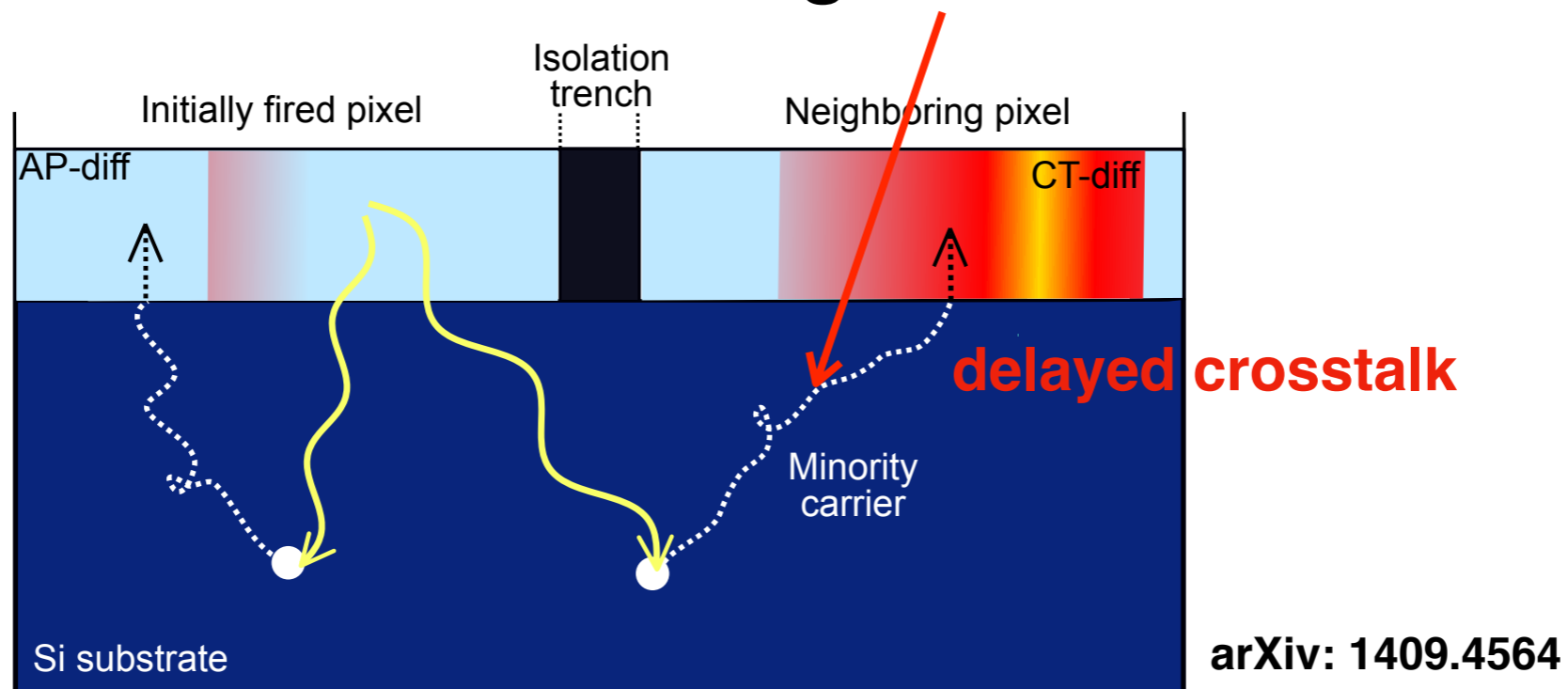
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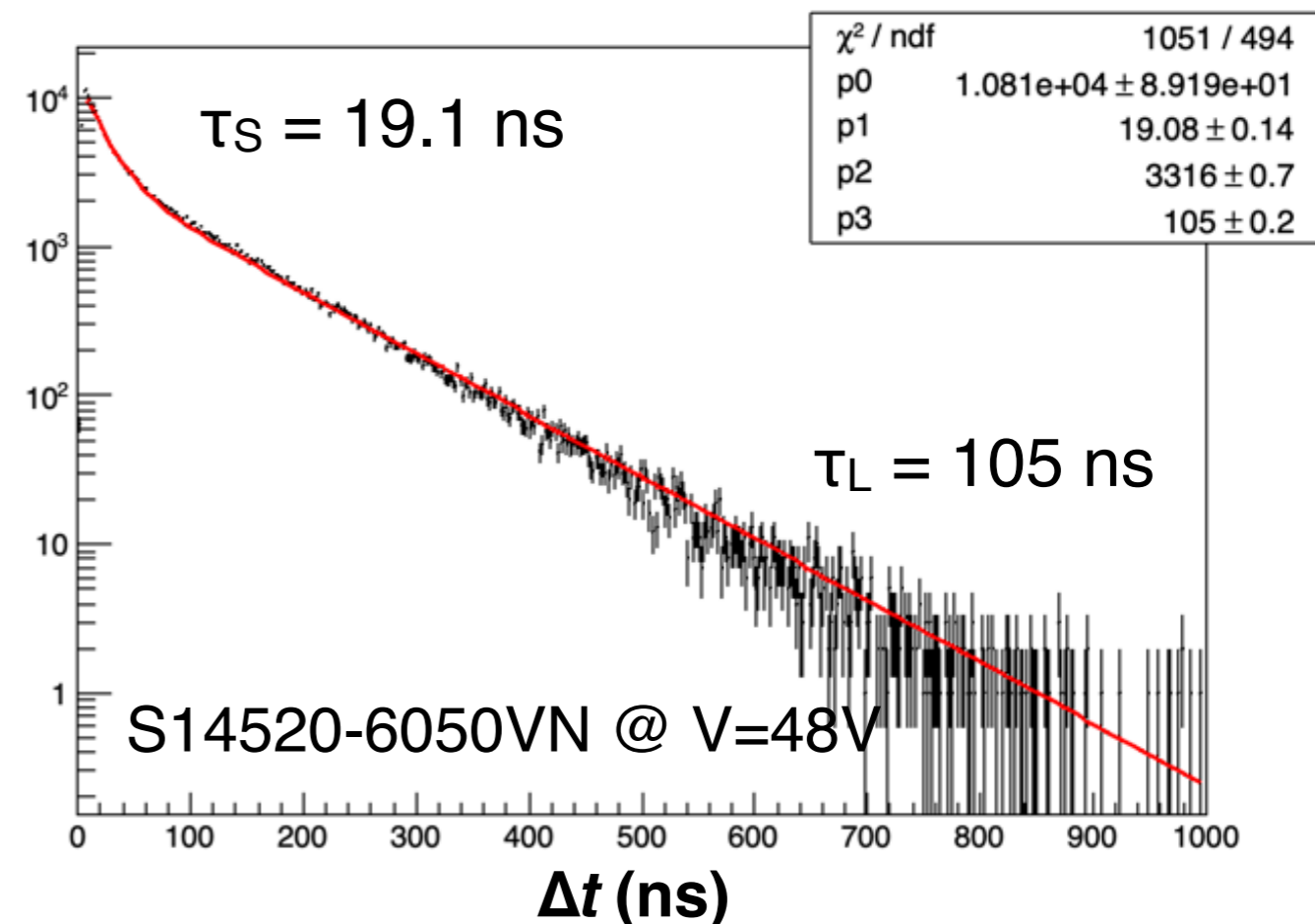
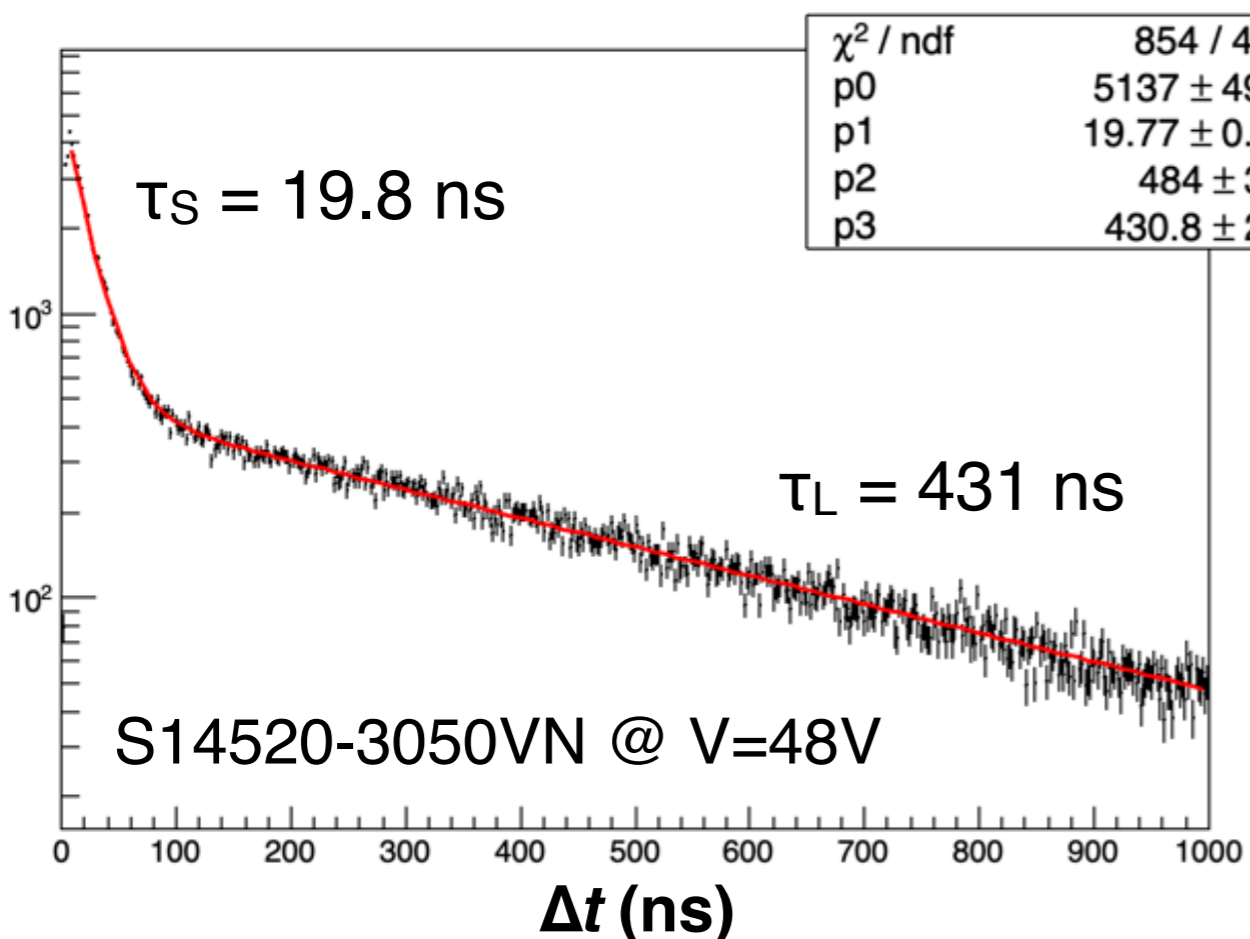
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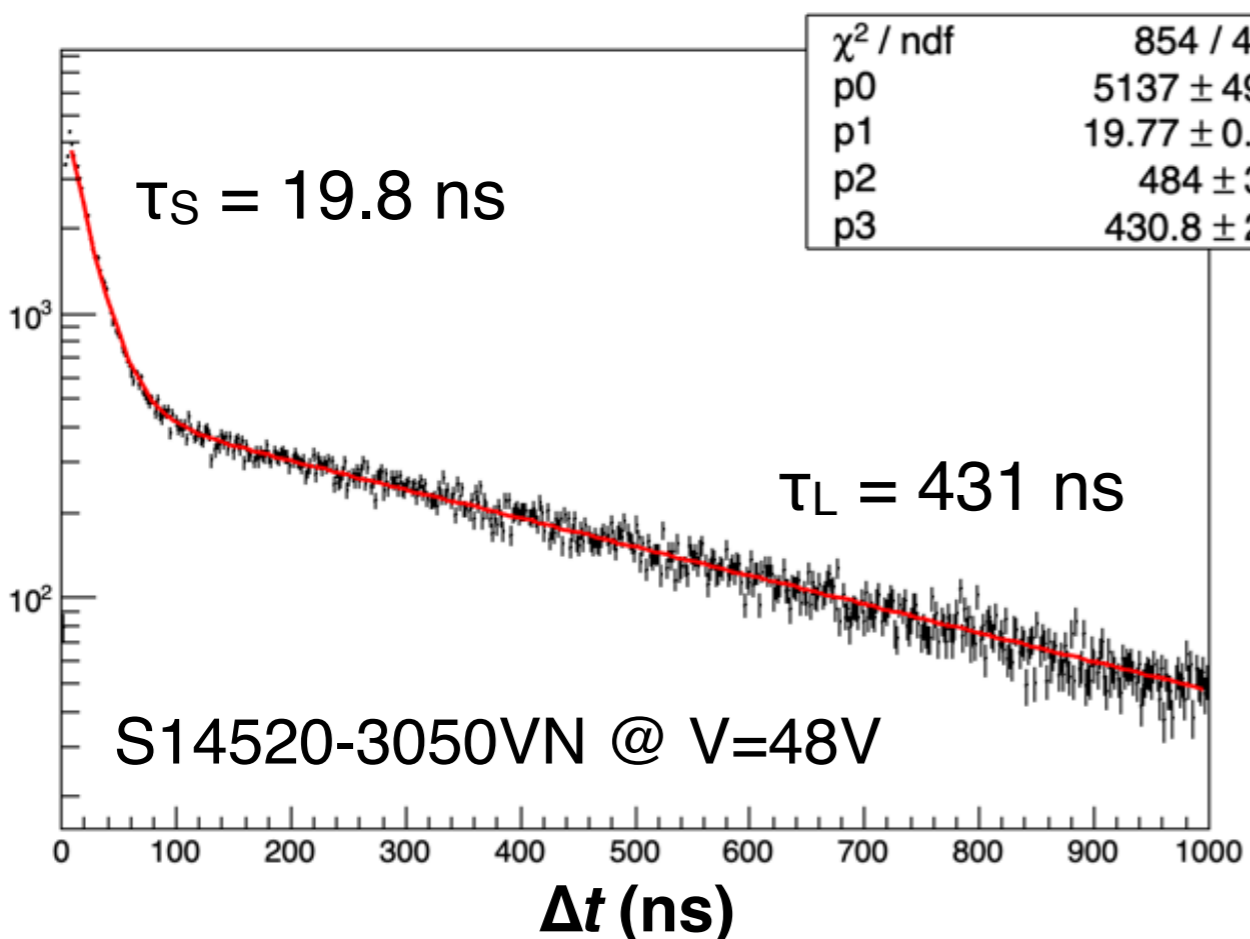
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- ❖ How about the crosstalk thorough the backside?



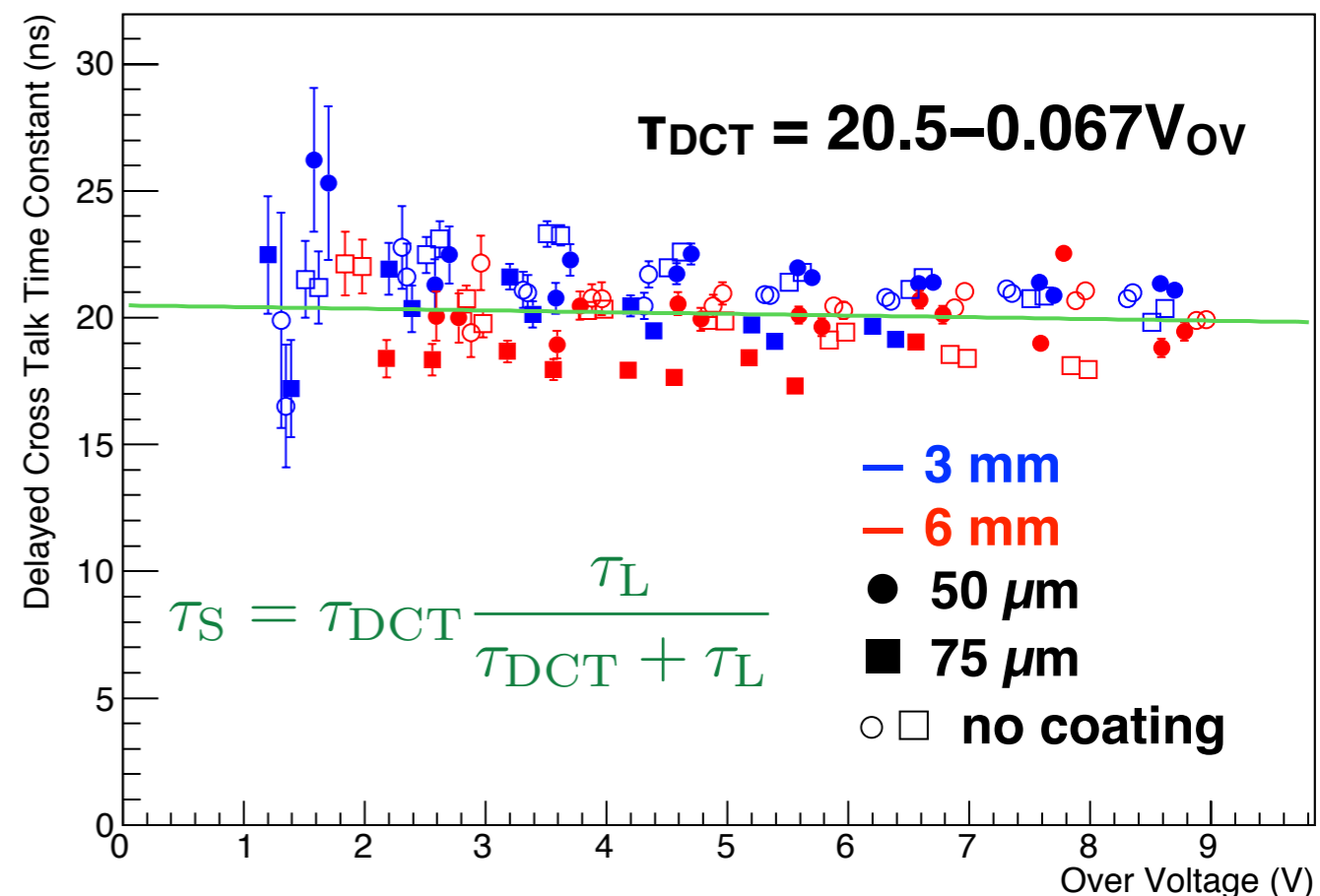
- ❖ Distribution of the time difference between two pulses show two exponential component with different time constants
- ❖ Relatively long time constant is due to dark counts
- ❖ **Short time component is mainly due to delayed crosstalk**
 - ◆ Short time constant is not heavily dependent on the over voltage
 - ◆ Afterpulse is negligible in these SiPMs



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JPS Meeting, SEP 15, 2020

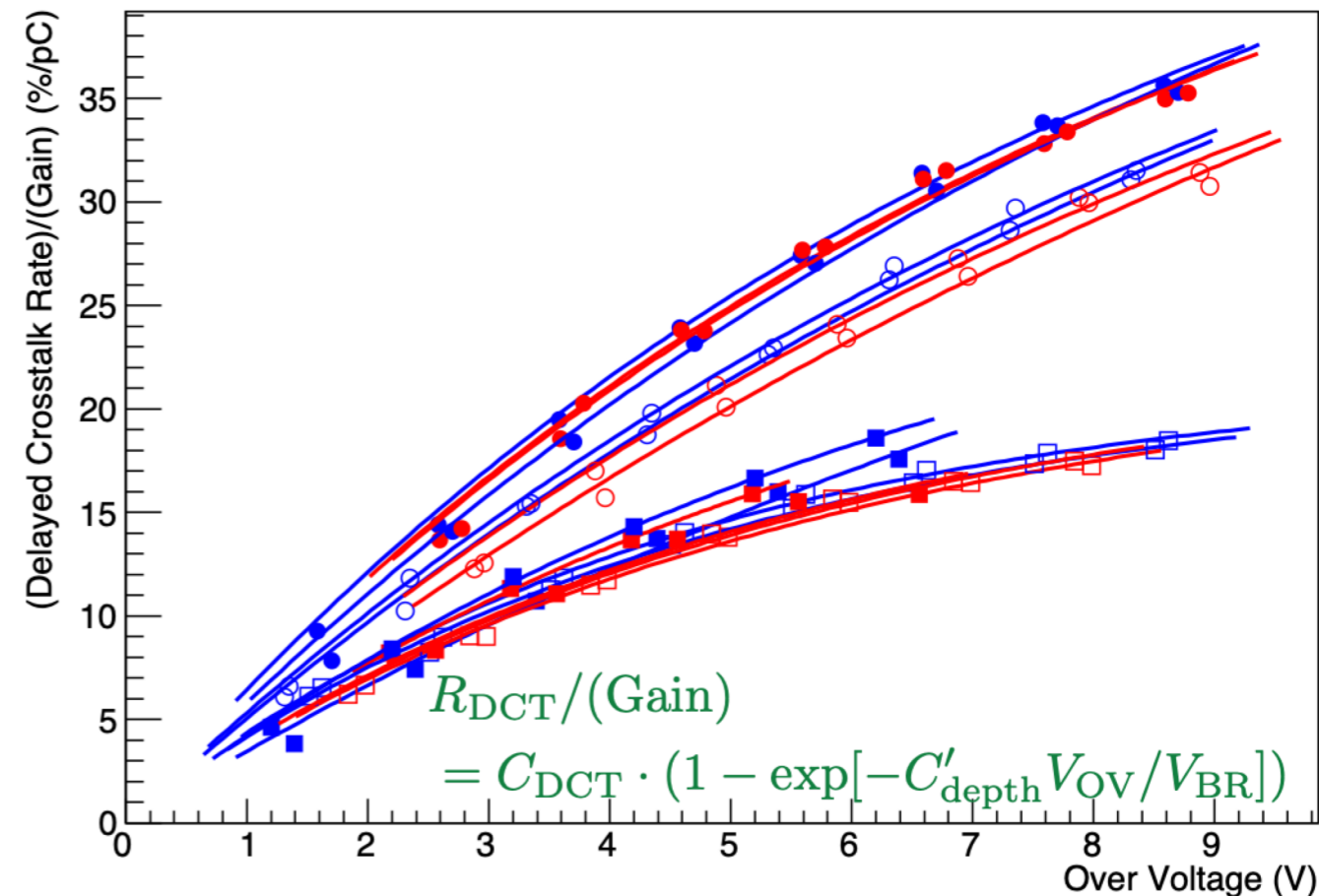
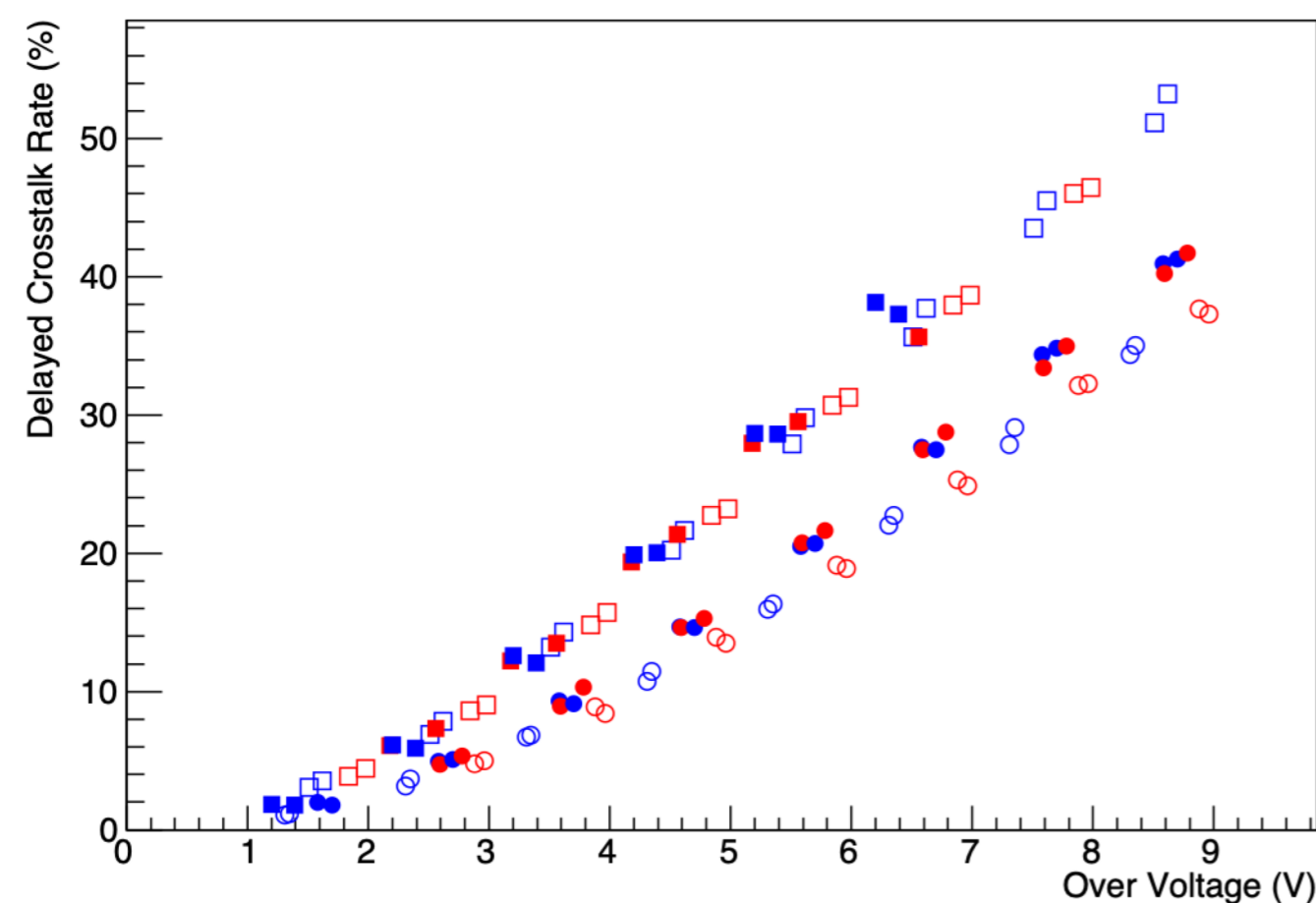


❖ Delayed crosstalk rate (R_{DCT}) is calculated as

$$R_{DCT} = \frac{N_S}{N_S + N_L}$$

N_S : # of event with short time constant
 N_L : # of event with long time constant

- ❖ There is no significant difference due to coating
- ❖ C_{DCT} is smaller for 75 μm cells (**smaller crosstalk efficiency**)
- ❖ C_{DCT} is larger than C_{OCT} , which means total amount of delayed crosstalk is larger than optical cross talk



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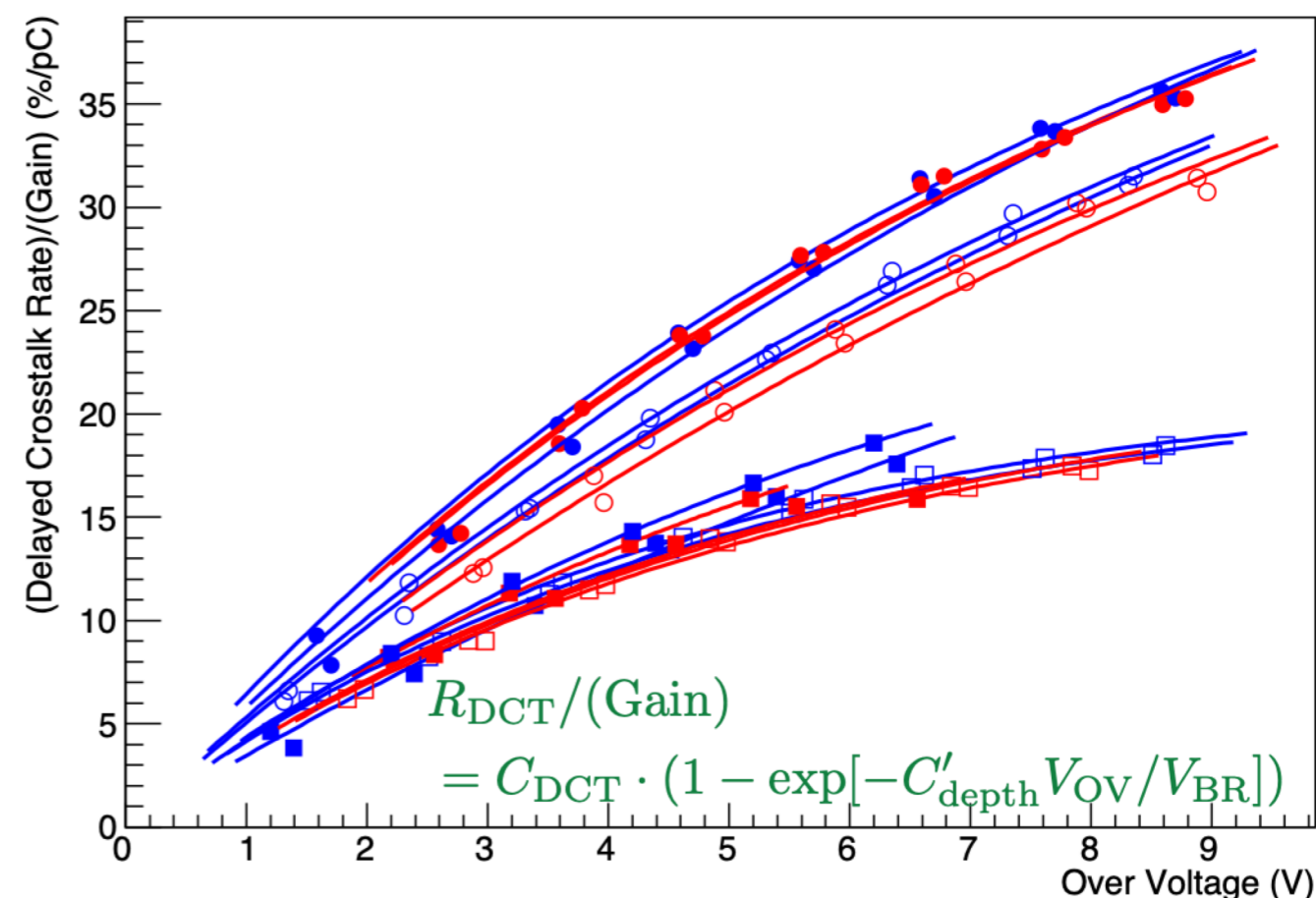
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Product ID	C_{DCT}	C_{Depth}
S14520-3050VS	59	3.4
S14520-3050VN	53	3.6
S14520-6050VS	55	4.7
S14520-6050VN	62	3.2
S14520-3075VS	37	4.5
S14520-3075VN	27	8.6
S14520-6075VS	26	6.6
S14520-6075VN	23	7.2



- ❖ There are some missing events for $\Delta t < 6$ ns
 - ❖ These events may be recognized as “prompt” crosstalk
- ❖ Ratio of (Missing Event Rate)/(Apparent Optical Crosstalk)
 - ❖ Ratio is more than 1 and constant for SiPMs without coating
 - ❖ Apparent crosstalk may be accounted for by missing events for SiPMs without coating

$$\frac{N_{\text{Missing}}}{N_S + N_L} / \frac{N(\geq 1.5\text{p.e.})}{N(\geq 0.5\text{p.e.})}$$

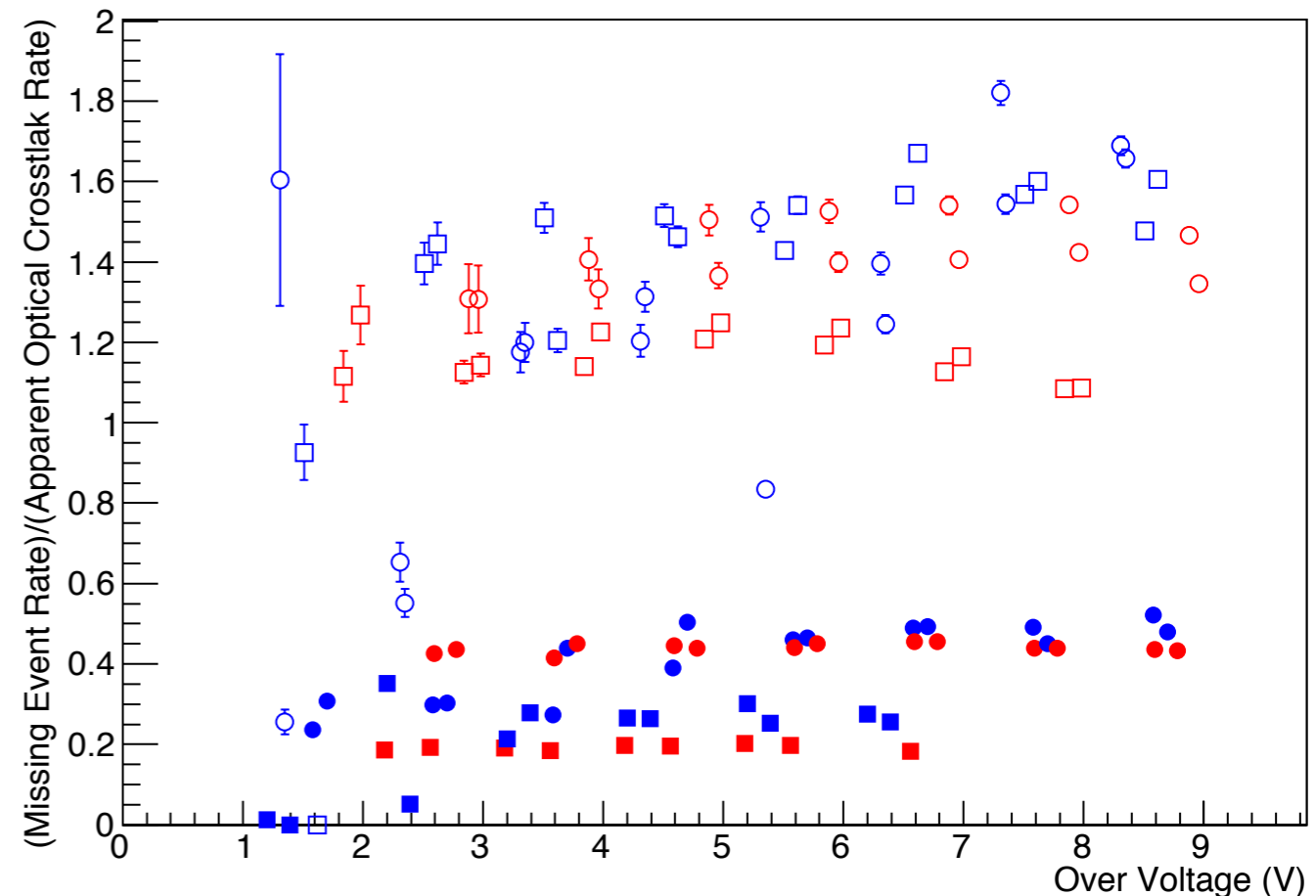
Delay Time

Missing events

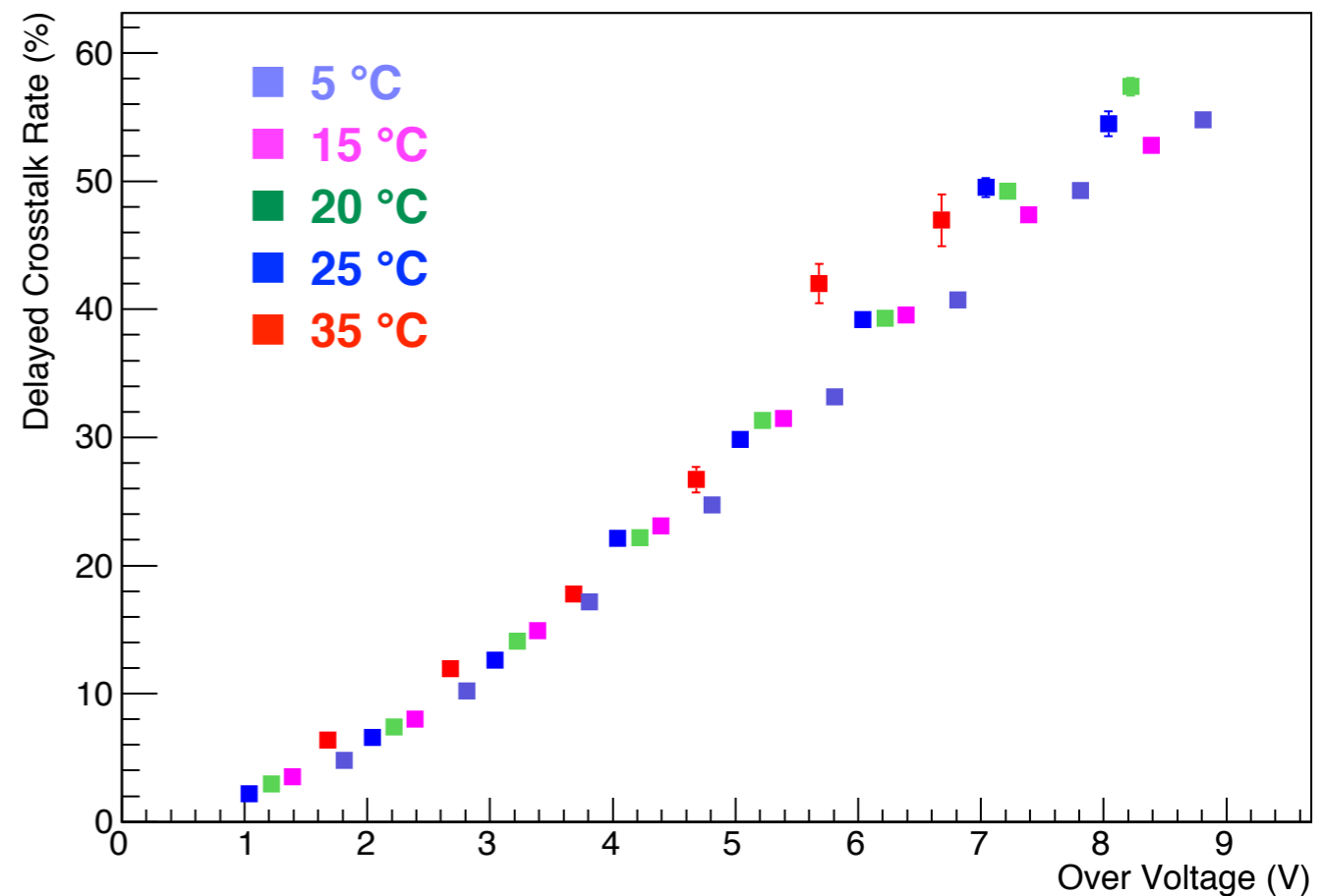
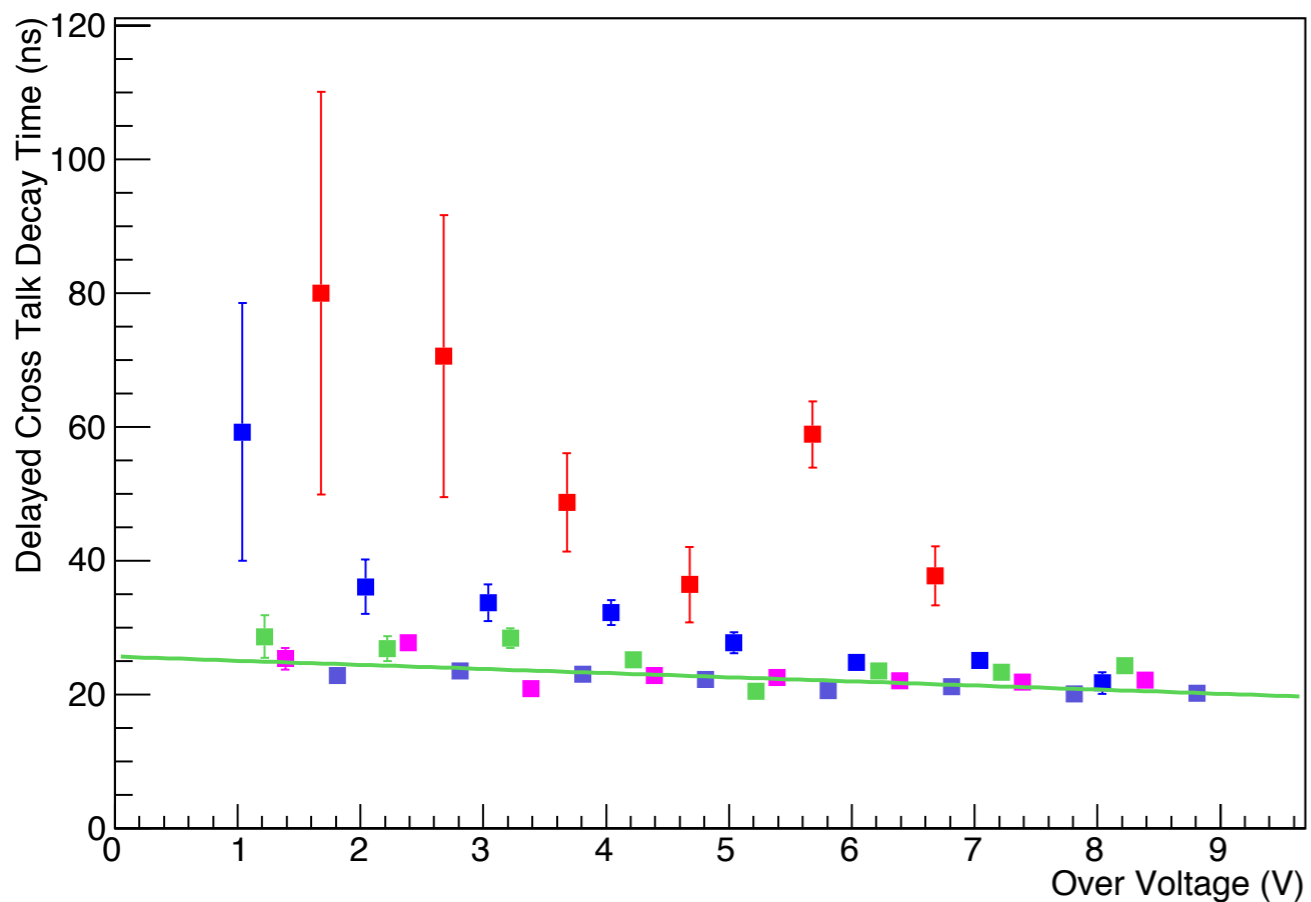
χ^2 / ndf	96 / 93
p0	5533 ± 40.1
p1	477.3 ± 13.1
p2	443 ± 38.6

S14520-3050VN @ V=48V

Δt (ns)



- ❖ No visible dependence on temperature for
 - ♣ delayed crosstalk time constant
 - ♣ delayed crosstalk rate



- ❖ **Optical crosstalk rate is significantly affected by resin coating**
 - ❖ Seed photons propagate through resin coating
 - ❖ **Smaller device size and thicker coating** reduce OCT rate
 - ❖ Larger cell size increase OCT rate due to larger gain
 - ❖ **No coating** significantly reduces OCT rate
- ❖ **Delayed crosstalk rate is greater than the optical crosstalk**
 - ❖ Delayed crosstalk is indecent of the resin thickness
 - ❖ Time constant of delayed crosstalk is ~ 20 ns and independent of the over voltage
 - ❖ Apparent cross talk will increase if the pulse width is not much shorter than 20 ns
 - ❖ **Early component of the delayed crosstalk may account for the remaining crosstalk for SiPMs without resin coating**